

Japan FPD Materials & Components Committee Meeting Summary and Minutes

SEMI Japan Standards Winter 2013 Meetings

Friday, February 8, 2013 15:00-17:00

SEMI Japan, Tokyo, Japan

Next Committee Meeting

Friday, April 12, 2013, 15:00-17:00

Campus Innovation Center (Yamagata University Tokyo Satellite), Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Hisashi Aruga (Seiko Epson), Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm)

SEMI Staff: Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Nitto Denko	Akada	Yuzo	Konica Minolta Optics	Ochi	Keizo
Yamagata University	Furukawa	Tadahiro	Fujifilm	Shibahara	Yoshi
Teijin Chemicals	Itoh	Haruhiko	Japan Display Central	Watanabe	Ryoichi
Otsuka Electronics	Kawaguchi	Akira	SEMI Japan	Tejima	Naoko

** alphabetical order by last name*

Table 2 Leadership Changes

None

Table 3 Ballot Results

None

Table 4 Authorized Ballots

<i>Document #</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
5552	Cycle 3, 2013	FPD Color Filter TF	Reapproval of SEMI D13-0708, Terminology for FPD Color Filter Assemblies
5553	Cycle 3, 2013	FPD Color Filter TF	Reapproval of SEMI D29-1101, Test Method for Heat Resistance in Flat Panel Display (FPD) Color Filters
5554	Cycle 3, 2013	FPD Color Filter TF	Reapproval of SEMI D30-0707, Test Method for Light Resistance in Flat Panel Display (FPD) Color Filters

Table 5 Authorized Activities

<i>Document #</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
5550	SNARF	Flexible Display TF	New Standard: Guide for Dimensional Measurement of Plastic Films
5551	SNARF	Flexible Display TF	New Standard: Measurement Method of Water Vapor Transmission Rate for Plastic Films and Sheets with High Barrier Properties for Electronic Devices
5552	SNARF	FPD Color Filter TF	Reapproval of SEMI D13-0708, Terminology for FPD Color Filter Assemblies
5553	SNARF	FPD Color Filter TF	Reapproval of SEMI D29-1101, Test Method for Heat Resistance in Flat Panel Display (FPD) Color Filters
5554	SNARF	FPD Color Filter TF	Reapproval of SEMI D30-0707, Test Method for Light Resistance in Flat Panel Display (FPD) Color Filters
5555	SNARF	Polarizing Film TF	Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film

Note: SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 6 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C121102-01	Chairs	To work on the documents of substrate and backlight for five-year review
FPD M&C121102-02	SEMI Japan Staff	To ask, through SEMI Korea Staff, members of FPD Committee in Korea what they want to do with respect to D41; - should be maintained or - can be "Inactive" document
FPD M&C130208-01	SEMI Japan Staff	To create an opportunity to explain about the Revised SEMI Regulations & Procedure Guide.
FPD M&C130208-02	SEMI Japan Staff	To submit reapproval ballot of SEMI D13 for Cycle 3, 2013
FPD M&C130208-03	SEMI Japan Staff	To submit reapproval ballot of SEMI D29 for Cycle 3, 2013
FPD M&C130208-04	SEMI Japan Staff	To submit reapproval ballot of SEMI D30 for Cycle 3, 2013

1 Welcome, Reminders, and Introductions

Tadahiro Furukawa, committee co-chair, called the meeting to order at 15:00. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI staff, Naoko Tejima.

3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on November 2, 2012.

It was pointed that the last line (Mechanical Stress Test was ...) of 6.3 should be deleted.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Yoshi Shibahara (Fujifilm) / Ryoichi Watanabe (Japan Display Central)

Discussion: None

Vote: 6 in favor and 0 opposed. **Motion passed.**

Attachment: 01_JA_FPD_M&C_Previous_Mtg_Minutes_130208

4 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2013 Calendar of Events, NA Standards Spring 2013 Meetings, 2013 Critical Dates for SEMI Standards Ballots, SEMI Standards Publications, ISC A&R SC Summary, New Standards Ballot and Membership Systems, New Ballot Formatting Templates, Style Manual and Compilation of Terms, Revised SEMI Regulations & Procedure Guide and Contact Information.

Action Item: SEMI Staff to create an opportunity to explain about the Revised SEMI Regulations & Procedure Guide.

Attachment: 02_SEMI_Staff_Report_130208

5 Liaison Reports

5.1 Japan Regional Standards Committee (JRSC)

No report was provided.

5.2 Korea FPD Committee Report

Naoko Tejima reported for the Korea FPD Committee. This report included Leadership, Organization Chart, Meeting Information, Ballot Results, Upcoming Ballots, Subcommittee/TF/WG Reports, Contact Information.

Attachment: 03_KR_FPD_Liaison_Report_130208

5.3 Taiwan FPD Committee Report

Naoko Tejima reported for the Taiwan FPD Committee. This report included Leadership, Organization Chart, Meeting Information, New SNARFs, New Task Force, Upcoming Ballots, FPD Committee Highlights, Contact Information. Of note:

- GCS approval system seems to be used too much recently. It should not be used unless it's really necessary.

Attachment: 04_TW_FPD_Liaison_Report_130208

6 Task Force Reports

6.1 Polarizing Film Task Force

Yuzo Akada reported for the Polarizing Film Task Force. Of note:

- *Doc.#5425, Revision to SEMI D46-0706: Terminology for FPD Polarizing Films* passed the ISC A&R SC for procedural review and will be published as SEMI D46-0213 this month.
- A new SNARF "*Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film*" was presented to the committee for approval.
- TF will start to discuss whether there are the new standards should be developed including the new items like the touch screen and the items which have been discussed so far.

Motion: To approve a new SNARF to revise SEMI D50-0707

By / 2nd: Yuzo Akada (Nitto Denko) / Yoshi Shibahara (Fujifilm)

Discussion: None

Vote: 6 in favor and 0 opposed. **Motion passed.**

Attachment: 05_SNARF_for_Revision_to_D50_130208

6.2 Backlight Task Force Task Force

No report was provided

6.3 Flexible Display Task Force

Tadahiro Furukawa reported for the Flexible Display Task Force. Of note:

- Two new SNARFs as below were presented to the committee for approval.

Motion: To approve a new SNARF to develop the New Standard, “Guide for Dimensional Measurement of Plastic Films”

By / 2nd: Haruhiko Itoh (Teijin Chemicals) / Keizo Ochi (Konica Minolta Optics)

Discussion: None.

Vote: 6 in favor and 0 opposed. **Motion passed.**

Motion: To approve a new SNARF to develop the New Standard, “Measurement Method of Water Vapor Transmission Rate for Plastic Films and Sheets with High Barrier Properties for Electronic Devices”

By / 2nd: Haruhiko Itoh (Teijin Chemicals) / Keizo Ochi (Konica Minolta Optics)

Discussion: It was recognized that the use of patented technology or a copyrighted item(s) is not required.

Vote: 6 in favor and 0 opposed. **Motion passed.**

Attachment: 06_SNARF_for_New_Std_Guide_for_Dimensional_Measurement..._130208

07_SNARF_for_New_Std_Measurement_Method_of_Water_Vapor_Transmission_Rate..._130208

6.4 Color Filter Task Force

Naoko Tejima reported for the *Color Filter Task Force* on behalf of Task Force Leader. Of note:

- Three new SNARFs as below were presented to the committee for approval.

Motion: To approve a new SNARF to reapprove SEMI D13-0708, “Terminology for FPD Color Filter Assemblies” and to submit its reapproval ballot for Cycle 3, 2013

By / 2nd: Ryoichi Watanabe (Japan Display Central) / Yoshi Shibahara (Fujifilm)

Discussion: None

Vote: 6 in favor and 0 opposed. **Motion passed.**

Motion: To approve a new SNARF to reapprove SEMI D29-1101, “Test Method for Heat Resistance in Flat Panel Display (FPD) Color Filters” and to submit its reapproval ballot for Cycle 3, 2013

By / 2nd: Ryoichi Watanabe (Japan Display Central) / Yoshi Shibahara (Fujifilm)

Discussion: None

Vote: 6 in favor and 0 opposed. **Motion passed.**

Motion: To approve a new SNARF to reapprove SEMI D30-0707, “Test Method for Light Resistance in Flat Panel Display (FPD) Color Filters” and to submit its reapproval ballot for Cycle 3, 2013

By / 2nd: Ryoichi Watanabe (Japan Display Central) / Yoshi Shibahara (Fujifilm)

Discussion: None

Vote: 6 in favor and 0 opposed. **Motion passed.**

Action Item: SEMI Staff to submit reapproval ballot of SEMI D13 for Cycle 3, 2013.

SEMI Staff to submit reapproval ballot of SEMI D29 for Cycle 3, 2013.

SEMI Staff to submit reapproval ballot of SEMI D30 for Cycle 3, 2013.

Attachment: 08_SNARF_for_Reapproval_of_D13_130208

09_SNARF_for_Reapproval_of_D29_130208

10_SNARF_for_Reapproval_of_D30_130208

7 Old Business

7.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C121102-01	Chairs	To work on the documents of substrate and backlight for five-year review ... Open
FPD M&C121102-02	SEMI Staff	To ask, through SEMI Korea Staff, members of FPD Committee in Korea what they want to do with respect to D41; - should be maintained or - can be "Inactive" document ... Open

8 New Business

None

9 Action Item Review

9.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

10 Next Meeting and Adjournment

The next meeting of the Japan FPD Materials & Components Committee is scheduled for Thursday, April 11, 2013, 15:00-17:00, SEMI Japan, Tokyo, Japan or Friday, April 12, 2013, 15:00-17:00, Campus Innovation Center (Yamagata University Tokyo Satellite), Tokyo, Japan. It will be held together with Japan FPD Metrology Committee as the Joint Meeting.

>> It was decided that the next meeting of the Japan FPD Materials & Components Committee is scheduled for Friday, April 12, 2013, 15:00-17:00, Campus Innovation Center (Yamagata University Tokyo Satellite), Tokyo, Japan on February 15.

Respectfully submitted by:
 Naoko Tejima
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 SEMI Japan
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Minutes approved by:

Tadahiro Furukawa (Yamagata University), Co-chair	March 11, 2013
Yoshi Shibahara (Fujifilm), Co-chair	March 12, 2013

Table 8 Index of Available Attachments #1

#	<i>Title</i>
1	JA_FPD_M&C_Previous_Mtg_Minutes_130208
2	SEMI_Staff_Report_130208
3	KR_FPD_Liaison_Report_130208
4	TW_FPD_Liaison_Report_130208
5	SNARF_for_Revision_to_D50_130208
6	SNARF_for_New_Std_Guide_for_Dimensional_Measurement..._130208
7	SNARF_for_New_Std_Measurement_Method_of_Water_Vapor_Transmission_Rate..._130208
8	SNARF_for_Reapproval_of_D13_130208
9	SNARF_for_Reapproval_of_D29_130208
10	SNARF_for_Reapproval_of_D30_130208

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.